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A Study on Thermal Stability of Ga-doped ZnO Thin Films with a TiO₂ Barrier Layer

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Ga-doped ZnO (GZO) was substitutes of the SnO₂:F films on soda lime glass substrate in the photovoltaic devices such as CIGS, CdTe and DSSC due to good properties and low cost. However, it was reported that the electrical resistivity of GZO is unstable above 300°C in air atmosphere. To improve thermal stability of GZO thin films at high temperature above 300°C an TiO₂ thin film was deposited on the top of GZO thin films as a barrier layer by Pulsed Laser Deposition (PLD) method. TiO₂ thin films were deposited at various thicknesses from 25 nm to 100 nm. Subsequently, these films were annealed at temperature of 300°C, 400°C, 500°C in air atmosphere for 20 min. The XRD measurement results showed all the films had a preferentially oriented (0 0 2) peak, and the intensity of (0 0 2) peak nearly did not change both GZO (300 nm) single layer and TiO₂ (50 nm)/GZO (300 nm) double layer. The resistivity of GZO (300 nm) single layer increased from $7.6 \times 10^{-4} \Omega\text{m}$ (RT) to $7.7 \times 10^{-2} \Omega\text{m}$ (500°C). However, in the case of the TiO₂ (50 nm)/GZO (300 nm) double layer, resistivity showed small change from $7.9 \times 10^{-4} \Omega\text{m}$ (RT) to $5.2 \times 10^{-3} \Omega\text{m}$ (500°C). Meanwhile, the average transmittance of all the films exceeded 80% in the visible spectrum, which suggests that these films will be suitable for photovoltaic devices.

Keywords: Ga-doped ZnO, GZO, TiO₂, Barrier layer, Thin film, Pulsed laser deposition, PLD

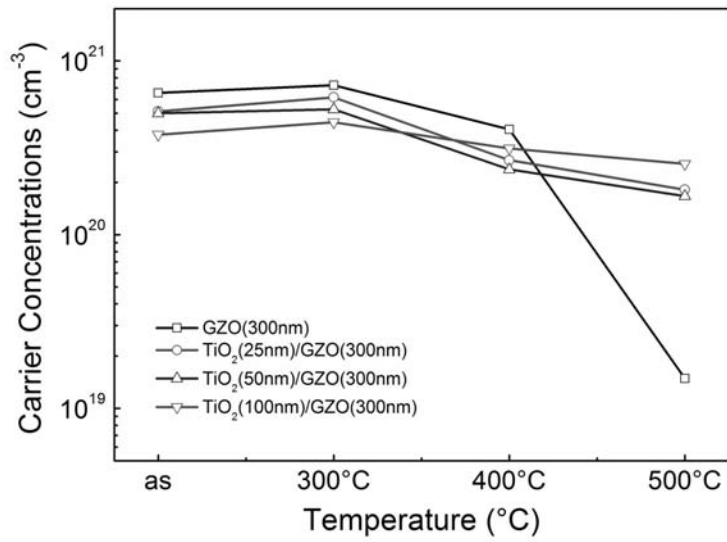


Fig. 1. Carrier Concentrations of GZO thin films with a TiO₂ barrier layer under different post-annealing temperatures.

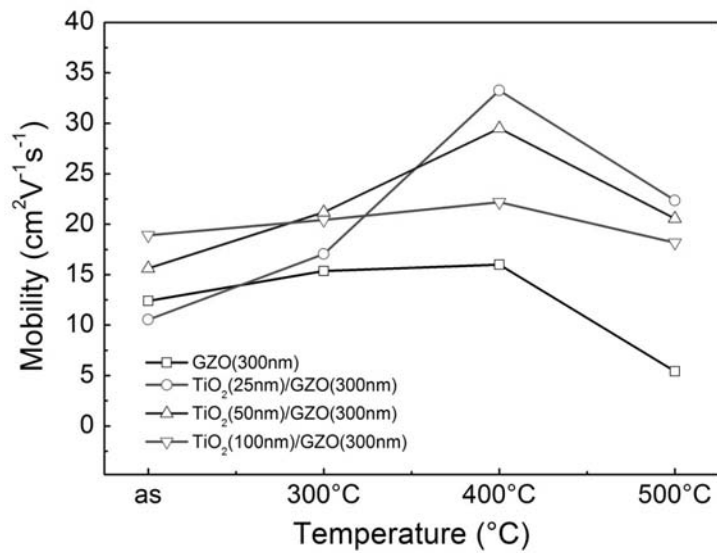


Fig. 2. Hole Mobility of GZO thin films with a TiO₂ barrier layer under different post-annealing temperatures.

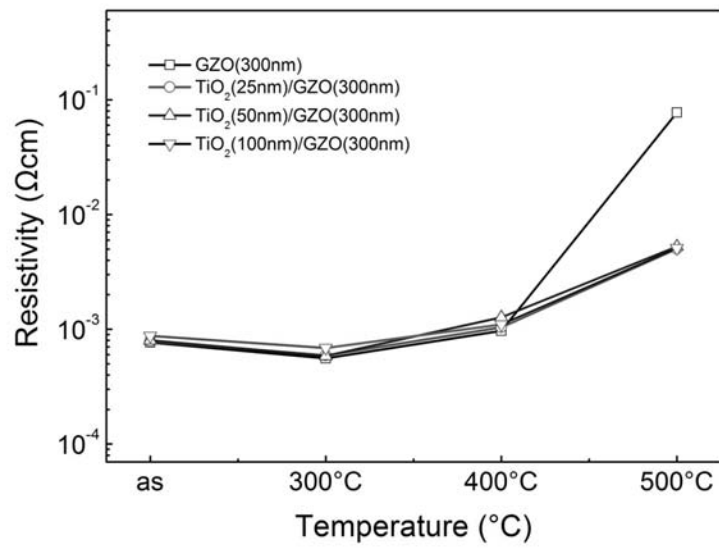


Fig. 3. Resistivity of GZO thin films with a TiO₂ barrier layer under different post-annealing temperatures.